



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Makoto AKIZUKI et al.

Serial No. 10/025,899

Filed December 26, 2001

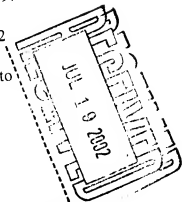
METHOD FOR FORMING GAS CLUSTER
AND METHOD FOR FORMING THIN FILM

: Confirmation No. 9191

: Docket No. 2001-1897

: Group Art Unit 1762

: Examiner B. Pianalto



LETTER RE INFORMATION DISCLOSURE STATEMENT

Assistant Commissioner for Patents,
Washington, D.C.

Sir:

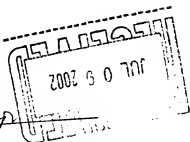
Kindly ignore the Information Disclosure Statement filed on June 5, 2002 in that the cited documents do not relate to the present application.

Respectfully submitted,

Makoto AKIZUKI et al.

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July 3, 2002

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TECHNOLOGY CLASSIFICATION